



Figure 1: clean image



Figure 2: pitted image

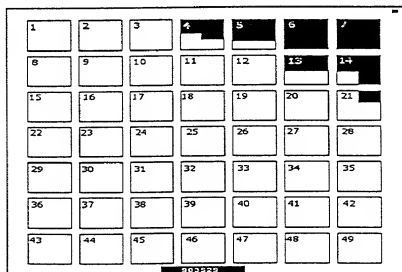


Figure 3: manual pit mapping

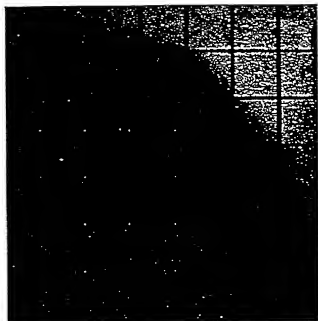


Figure 5: pitting on #7
corner with standard wafer
loading (# 7 is bottom of

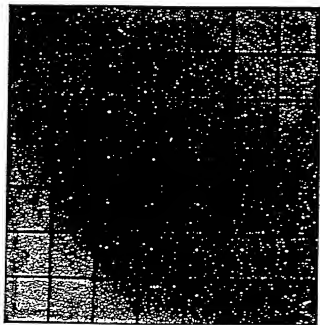


Figure 6: pitting on #43 corner
when wafer is loaded 180° from
standard loading (#43 is bottom
of the flowcell)

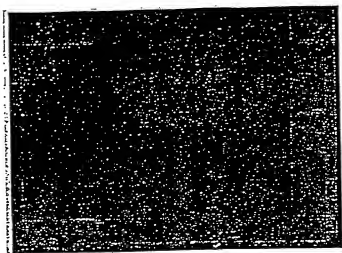


Figure 7: pit map from back side photolysis



Figure 8: Pit map from 10-sec
dry flow cell synthesis

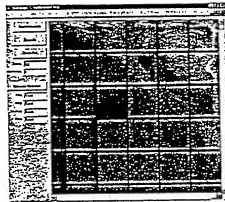


Figure 9: pit map from
standard 25-sec dry flowcell
synthesis



Figure 10: pit map from 75-sec
dry flowcell synthesis